

WHAT IS CLAIMED IS:

1. A thin film formation apparatus comprising:

a head portion having an ultrasonic oscillator; and

a nozzle filled with an application liquid for forming an EL layer.

2. A thin film formation apparatus comprising:

a head portion having an ultrasonic oscillator; and

a nozzle filled with an application liquid for forming an EL layer,

wherein said nozzle has a heater.

3. A thin film formation apparatus according to claim 2, wherein said nozzle has a

large internal diameter portion and a small internal diameter portion, and

said heater is formed in said small internal diameter portion.

4. A thin film formation apparatus according to claim 2, wherein the small internal diameter portion of the nozzle has a contact element.

5. A thin film formation apparatus according to claims 1 or 2, wherein said application liquid in said nozzle is pressurized by ultrasonic oscillations, and is pushed out

from said nozzle.

6. A method of manufacturing a self-light-emitting device, comprising the steps of: filling a nozzle with an application liquid for forming an EL layer; and

applying said application liquid to a pixel column in accordance with applying

ultrasonic oscillations or heat.

7. A method of manufacturing a self-light-emitting device according to claim 6, wherein:

5 said nozzle has a large internal diameter portion and a small internal diameter portion;

 said small internal diameter portion has a heater; and

 said heater applies heat to the application liquid filling the nozzle.

10 8. A method of manufacturing a self-light-emitting device, comprising the steps of :
 imparting ultrasonic oscillations to a nozzle of a head portion by using an ultrasonic oscillator; and

 imparting ultrasonic oscillations to an application liquid filling said nozzle by using said ultrasonic oscillator.

15 9. A method of manufacturing a self-light-emitting device according to claim 8, wherein a heater of said nozzle applies heat to said application liquid filling said nozzle.

20 10. A method of manufacturing a self-light-emitting device according to claims 6 or 8, wherein said application liquid is pushed out from said nozzle in accordance with pressurization, and is applied.

 11. A method of manufacturing a self-light-emitting device according to claims 6 or 8, wherein said application liquid is pushed out from said nozzle in accordance with: capillary

action; the weight of said application liquid; or pressure; and is applied.

12. A method of manufacturing a self-light-emitting device according to claims 6 or 8, wherein said application liquid filling said nozzle is applied in accordance with a contact
5 element of said nozzle contacting a bank.